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[54] **METHOD AND APPARATUS FOR AN INTEGRATED LASER BEAM SCANNER**

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[57]

ABSTRACT

A solid state laser beam scanning system having a single crystal silicon deflection and scanning mirror integrated with a laser diode. By combining the techniques of deep reactive ion etching of silicon with solder bump bonding techniques, completed and tested laser diodes are integrated with silicon substrates supporting micro-electro-mechanical systems layers.

20 Claims, 11 Drawing Sheets

